

08-24-06

AF-  
[10191/1629] JEW**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Inventor(s) : LAERMER et al. Confirmation No.: 5642  
 Serial No. : 09/720,761  
 Filed : March 26, 2001  
 For : METHOD OF PLASMA ETCHING OF SILICON  
 Examiner : K. Chen  
 Art Unit : 1765  
 Customer No. : 26646

Mail Stop AF  
 Commissioner for Patents  
 P.O. Box 1450  
 Alexandria, VA 22313-1450

**NOTICE OF APPEAL AND REQUEST FOR EXTENSION OF TIME**  
**PURSUANT TO 37 C.F.R. §1.136(a)**

SIR:

Applicants hereby appeal the Examiner's decision made in the Final Office Action dated February 22, 2006, finally rejecting claims 19, 21-24, 27-33 and 39. Applicants request a three-month extension of time, so that the three-month response period is extended from May 22, 2006 to August 22, 2006. The Commissioner is authorized to charge the \$1,020.00 three-month extension fee to the account of Kenyon & Kenyon LLP, Deposit Account No. 11-0600.

The Commissioner is hereby authorized to charge the payment of the 37 C.F.R. § 41.20(b)(1) Notice of Appeal fee of \$500.00, to **Kenyon & Kenyon LLP**, Deposit Account No. 11-0600. Any additional fees deemed necessary should also be charged to Deposit Account No. 11-0600. An additional copy of this Notice is enclosed for that purpose.

Dated: 8/22/06

Respectfully submitted,  
 KENYON & KENYON LLP

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